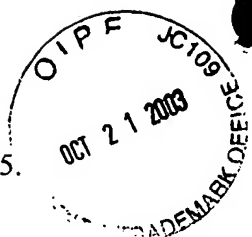


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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#80/B
10/30/03
Surler

In re Application of:

Yoshiyuki NAGAI et al.

Application No.: 09/839,139

Filed: April 23, 2001

For: LASER OSCILLATION APPARATUS, EXPOSURE
APPARATUS, SEMICONDUCTOR DEVICE

MANUFACTURING METHOD; SEMICONDUCTOR
MANUFACTURING FACTORY, AND EXPOSURE
APPARATUS MAINTENANCE METHOD

)
: Examiner: M. Landau
)
: Group Art Unit: 2815
)
: Confirmation No.: 1616
)
: October 21, 2003
)
:)

Mail Stop RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application
as follows:

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